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TW		5,837,426	11/17/1998	TSENG	, et al.				
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TN	٠	EP1045291A3	10.01.200 1	EUROPE					
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PAGE 11/20 \* RCVD AT 11/29/2004 3:19:24 PM [Eastern Standard Time] \* SVR:USPTO-EFXRF-1/2 \* DNIS:8729306 \* CSID:845 892 6363 \* DURATION (mm-ss):05-32